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Apparent zeta potential of nano-porous Al₂O₃ film deposited on different substrates in streaming potential method

Akio Sayano^{1,*} ^(b), Tadashi Shiota¹, Akio Nishiyama¹, Kouichi Yasuda¹, and Kazuo Shinozaki¹

¹ School of Materials and Chemical Technology, Tokyo Institute of Technology, Meguro-ku, Tokyo 152-8550, Japan

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ABSTRACT

Al₂O₃ films were coated on SUS304L stainless steel and fused silica substrates using chemical solution deposition. Continuous pores with a diameter of approximately 2 nm were observed through the measurement of the pore diameter distribution in the Al₂O₃ films using N₂ gas adsorption. The zeta AQI potential of the Al_2O_3 film was measured using the streaming potential method, and the effect of the substrate material on the zeta potential was investigated. Initially, the measured zeta potential of the Al_2O_3 films was + 40 to + 50 mV, which was the same for both the SUS304L and fused silica substrates. However, the zeta potential of the Al_2O_3 film on the fused silica substrate decreased significantly with repeated measurements. Elemental analysis of the Al₂O₃ film in the depth direction using dynamic secondary ion mass spectroscopy showed that both K and Cl contents increased after zeta potential measurements were taken. Moreover, the zeta potential of a specimen impregnated with KCl electrolyte solution under vacuum exhibited no dependence on the number of measurements taken. It was thereby considered that the decrease in the zeta potential with repeated measurements was caused by the gradual penetration of the electrolyte solution into the pores, which eventually reached the fused silica substrate. This is a characteristic phenomenon observed when the zeta potential of a film that contains continuous pores is measured using the streaming potential method.

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Author Proof

41 Introduction42

Solid particles in a fluid can deposit and accumulate
on the components of equipment and systems that
employ fluids, such as nuclear power plants, and
obstruct the flow of the fluid. As a result, the

performance of the equipment or system may be47degraded, and damage to the equipment may result.48Therefore, there is a demand for technology to sup-49press the deposition of solid particles in fluids on the50components [1–3].51

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Address correspondence to E-mail: sayano.a.aa@m.titech.ac.jp

52 Zeta potential control is a method to suppress the 53 deposition of solid particles onto the surfaces of 54 parts. In this method, a film with the same zeta 55 potential sign as that of the solid particles in the fluid 56 is coated on the components, thereby creating a 57 repulsive force between the solid particles in the fluid 58 and the component surface [1-6]. This is a unique 59 and excellent method that takes advantage of the 60 intrinsic characteristics of the material and does not 61 consume energy to suppress deposition.

The chemical solution deposition (CSD) method considered in this study is a well-established practical process to coat large parts [7–11]. In the CSD method, a ceramic film is formed on a substrate by first depositing a ceramic precursor solution on the substrate surface and then applying heat treatment to decompose the precursor. This process is advantageous in that it does not require special equipment and is applicable to large parts with complex shapes. However, films formed using CSD typically have a characteristic microstructure with continuous pores [22–24].

74 Many of the large parts that are considered in this 75 study are metallic. Therefore, accurate measurement 76 of the zeta potential of a film containing continuous 77 pores that is coated on a metal substrate is necessary. 78 Electrophoresis is also commonly used to evaluate 79 zeta potential, but this method involves the applica-80 tion of a high voltage to the electrolyte solution and is 81 therefore difficult to use in electrically conductive 82 substrate [13]. The streaming potential method [12] 83 can be used to measure the zeta potential of a film 84 coated on a metal substrate. In the streaming poten-85 tial method, an electrolyte solution is passed between 86 two specimens placed on either side of a narrow gap and the resulting voltage or current is measured. A 87 88 voltage is not applied in this procedure, and thus, 89 evaluation of the zeta potential of a film on a metal 90 substrate should be possible. This method requires 91 the application of pressure to move the electrolyte 92 solution. As a result, the electrolyte solution may 93 penetrate the pores of the film, resulting in interac-94 tions between the electrolyte solution and the sub-95 strate that could affect the measured zeta potential.

96 Very few reports discuss the zeta potential of a film 97 containing continuous pores that is coated on a metal 98 substrate by the use of the streaming potential 99 method to measure. Lorenzetti et al. [14] coated a 100 TiO₂ film with a thickness of 30 μ m on a Ti metal 101 substrate via a hydrothermal method using a Ti alkoxide precursor, and then evaluated the zeta 102 potential using the streaming potential method. 103 Specifically, they measured the electrical conductivity 104 between the electrodes for different gap distances 105 between the specimens. They concluded that the 106 streaming current flows in the pores in the film, 107 according to data extrapolated to zero gap distance. 108 Moreover, they corrected these data to obtain accu-109 rate zeta potential. However, the film investigated in 110 their study was relatively thick (approximately 111 30 µm), and they did not consider the interaction 112 between the electrolyte solution that penetrated the 113 film pores and the substrate. Daiguji et al. published 114 a related report on the behavior of electrolyte solution 115 in a SiO₂ nanotube. They placed a KCl electrolyte 116 solution at both ends of a SiO₂ nanotube with a 117 diameter of 30 nm and a length of 5 µm, and then 118 analyzed the behavior of the K⁺ and Cl⁻ ions using a 119 two-dimensional continuum equation [15]. They 120 concluded that K⁺ ions penetrated the nanotube, but 121 Cl⁻ ions were unable to penetrate because the SiO₂ 122 nanotube surface was negatively charged in the KCl 123 electrolyte solution. However, these results do not 124 consider any pressure difference and therefore are 125 not applicable in cases where pressure is applied, 126 such as the streaming potential method. 127

Determining whether the substrate has any effect 128 on the zeta potential of the film is important to 129 accurately measure the zeta potential of a film with 130 131 continuous pores on a metal substrate. To this end, 132 stainless steel and fused silica were chosen as substrates. An Al₂O₃ film was coated on these substrates 133 using CSD, and the differences in the zeta potentials 134 of these specimens were examined by the streaming 135 potential method. 136

This report investigates for the first time the effect 137 of substrate type on the zeta potential of films coated 138 on the substrate. Furthermore, the origin of the 139 decrease in zeta potential with repeated measurements, a phenomenon discovered during the investigation, is discussed. 142

Materials and methods

Film formation

 The substrates used in this study were SUS304L
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 [composition: C (0.021%), Cr (18.15%), Ni (9.06%), Mn
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 (0.98%), Si (0.64%), P (0.031%), and S (0.004%)] and
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An Al₂O₃ film was coated onto each substrate 151 152 using CSD. Figure 1 depicts the film preparation process. Both substrates were ultrasonically cleaned 153 in acetone, immersed in an Al₂O₃ solution, diluted to 154 the specified concentration using pure water, and 155 then removed at a fixed rate of 2 mm s^{-1} . Pseudo-156 157 boehmite sol was used as the Al₂O₃ sol (10A, Kawaken Fine Chemicals) and was obtained by the 158 159 hydrolysis of Al alkoxide. After dip-coating, the 160 specimens were dried at room temperature and heat-161 treated in an electric furnace at 773 K for 30 min in air at the rate of 10 K min⁻¹. Subsequently, the speci-162 163 mens were cooled in the furnace. The film thickness was controlled by repeating the above procedure. 164 165 Heat treatment conditions of 773 K and 30 min were determined to allow for the complete thermal 166 167 decomposition of the Al₂O₃ sol.

fused silica (ES, Tosoh Quartz). The substrate was in

the form of a rectangular plate, and the arithmetic

168 A self-supporting film was prepared using the 169 same Al₂O₃ sol in order to investigate the properties of this film. A silicone resin mold (inner dimensions: 170 171 diameter 60 mm × height 15 mm) was placed on a 172 plate of glass that had been coated with a 50-µm-thick 173 fluoropolymer layer. The Al₂O₃ sol described above 174 was poured into the mold and dried at 333 K for 5 h. 175 The obtained thin film was placed in a mullite crucible, and heat treatment was carried out under the 176 177 same conditions used to prepare the coated films 178 described above. A self-supporting film with a 179 thickness of approximately 80 µm was obtained.

> Pseudo-boehmite sol Pure water Mixing 30 min at R.T. Dip coating 2 mm s⁻¹ drying R.T. 10 °C min⁻¹ Heat-treatment 500 °C, 30 min (in air)

Figure 1 Procedure for preparing films.

Evaluation

A specimen (dimensions $10 \times 20 \times 1 \text{ mm}^3$) was 181 prepared with an Al₂O₃ film coating on a fused silica 182 substrate using the process described above. The 183 specimen was embedded in resin, and the resulting 184 material was cut through the middle and polished 185 using waterproof abrasive paper. The cross-sectional 186 region of the coating was then machined using an ion 187 beam (SM09010CP, JEOL). The obtained cross section 188 of the coating was observed using a field emission 189 scanning electron microscope (FE-SEM; S-4700, 190 Hitachi). 191

The zeta potentials of the Al₂O₃ films coated on the 192 substrates were measured using the streaming 193 potential method (SurPASSTM 3, Anton Paar). Fig-194 ure 2 shows a schematic of the zeta potential mea-195 surement by the streaming potential method. A pH of 196 approximately 5.5 was maintained during the mea-197 surements by bubbling N₂ gas through the electrolyte 198 solution, as needed. The measurement temperature 199 was approximately 300 K, the electrolyte was a 1 mM 200 solution of KCl, and the gap between the samples 201 was approximately 100 µm. The pressure was 202 increased to a maximum of approximately 50000 Pa, 203 but the zeta potentials were calculated based on the 204 streaming current in the stable range of 20000-205 38000 Pa using the following Helmholtz-Smolu-206 chowski equation [16], 207

$$\zeta = dI/dP \times \eta/\varepsilon\varepsilon_0 \times L/A \tag{1}$$

209 where ζ is the zeta potential, *I* is the current, *P* is the pressure, η is the viscosity of electrolyte, ε is the rel-210 ative permittivity, ε_0 is the permittivity of vacuum, L 211 is the channel length, and A is the cross-sectional area 212 of channel. A polypropylene (PP) film with a thick-213 ness of 50 µm was placed opposite to the coated 214

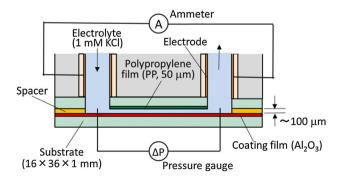


Figure 2 Schematic illustration of the testing apparatus for zeta potential by streaming potential method.



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215 specimen to be measured. Therefore, the apparent zeta potential obtained in the measurements was the 216 217 average of the values for the coated specimen and PP. 218 The zeta potential of the coated specimen was 219 derived using Eq. (2) below. The zeta potential of PP 220 (23.5 mV) was obtained beforehand using the same 221 conditions and equipment, by placing two PP films 222 opposite to each other.

$$\begin{aligned} \zeta_{\rm m} &= 1/2 \times \zeta + 1/2 \times \zeta_{\rm p} \\ \zeta &= 2 \times \zeta_{\rm m} - \zeta_{\rm p} \end{aligned} \tag{2}$$

224 where $\zeta_{\rm m}$ is the measured zeta potential, ζ is the zeta 225 potential of specimen, and $\zeta_{\rm p}$ is the zeta potential of 226 PP. Measurements were repeated six times to verify 227 the reproducibility of the data.

228 The pore distribution of the Al₂O₃ film was ana-229 lyzed using gas adsorption measurements (Autosorb-230 1, Quantachrome). Plate-shaped fused silica and 231 SUS304L specimens (dimensions: $22 \times 5 \times 1 \text{ mm}^3$) 232 were coated using the above process. Seven Al₂O₃ 233 films, total weighing 8-9 mg, were prepared for 234 testing. The N₂ adsorption isotherm at 77 K was 235 measured, and the pore distribution of the film was evaluated using the Barrett-Joyner-Halenda (BJH) 236 237 method [17]. A similar measurement was taken for a 238 self-supporting Al₂O₃ film weighing 173 mg. In 239 addition, the true density of the self-supporting 240 Al₂O₃ film was determined by helium displacement using Archimedes' principle. The film pore ratio *p* is 241 defined as 242

$$p = v/(v + (1/d)) \times 100$$
 (3)

244 where d is the true density and v is the total pore 245 volume that can be determined by pore distribution 246 analysis.

247 **Results and discussion**

248 Film characterization

Figure 3 shows an example of a cross-sectional FE-249 250 SEM image. In this case, the Al₂O₃ film was coated by single immersion in 6.7 wt.% Al₂O₃ sol. The film was 251 252 firmly attached to the substrate. The thickness of the film was approximately 0.5 μ m, and the weight of the 253 film per unit surface area was 1.04 g m^{-2} , as derived 254 from the change in weight after coating and the 255 256 specimen surface area. Subsequent film thicknesses 257 were calculated using the weight change after

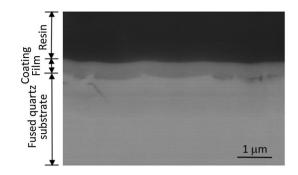


Figure 3 FE-SEM image of the cross section of an Al₂O₃ film coated on a fused silica substrate.

coating, assuming that the weight of the film per unit 258 surface area was proportional to the film thickness. 259

Figure 4 shows the relationship between the 260 number of dipping cycles and the film thickness for 261 the SUS304L and fused silica substrates. The alumina 262 sol concentration was 6.7 wt.%, and the dimensions 263 of the specimens were $16 \times 36 \times 1 \text{ mm}^3$. The film 264 thickness increased linearly with the number of dip-265 ping cycles for both substrates. There was no signif-266 icant difference in the manner in which the Al₂O₃ sol 267 deposited on these substrates. 268

Figure 5a shows the pore diameter distribution of 269 Al₂O₃ films coated on SUS304L and fused silica 270 substrates, and that of a self-supporting Al₂O₃ film. 271 Figure 5b plots the cumulative pore volume of the 272 Al₂O₃ film coated on a fused silica substrate. The pore 273 diameter distribution showed a sharp peak at about 274 2 nm in all cases, demonstrating that the Al₂O₃ films 275 in this study had pores with a uniform diameter of 276 approximately 2 nm. The cumulative pore volume of 277 the Al₂O₃ film on a fused silica substrate was 278 $0.33 \text{ cm}^3 \text{ g}^{-1}$, and the true density of self-supporting 279

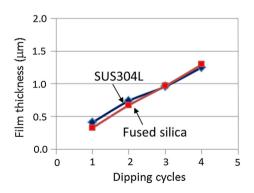
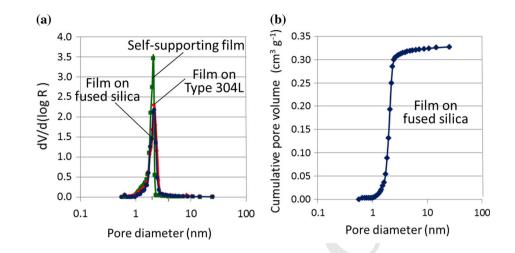


Figure 4 Relationship between number of dipping cycles and thickness of Al_2O_3 films coated on SUS304L and fused silica substrates (sol: pseudo-boehmite 6.7 wt.%, treatment: 500 °C, 30 min).

Figure 5 a Pore diameter distribution for Al₂O₃ films coated on substrates and self-supporting Al₂O₃ film.
b Cumulative pore volume for Al₂O₃ film coated on a fused silica substrate.



Measurement of zeta potential

280 film, as determined by helium displacement using Archimedes' principle, was 3.01 g cm⁻³. The porosity 281 of the Al₂O₃ film coated on a fused silica substrate 282 was 50%, assuming that the true density of the Al_2O_3 283 film was the same for the film on the substrate and 284 285 the self-supporting film. The microstructure of the Al₂O₃ film in this study was determined to consist of 286 287 small pores, with a high porosity.

Guo et al. [22] formed a Nb₂O₅ film on electrically 288 289 conductive glass by CSD using NbCl₅ as the raw 290 material; then, they measured the pore diameter 291 using N₂ adsorption. They found that the pore diameter varied widely (from 3 to 23 nm) depending 292 293 on the heat treatment temperature and that the 294 porosity derived from the cumulative pore volume 295 and true density value was 16-25%. Stathatos et al. 296 formed a TiO₂ film on a glass substrate using CSD. Ti alkoxide was used as a raw material, and the sur-297 298 factant TritonX-100 was included in the sol. The pore 299 diameter measured using N₂ adsorption was 6–9 nm, and the pore ratio derived from the cumulative pore 300 volume and true density value was 31-45% [23]. Choi 301 302 et al. also formed a TiO₂ film on a glass substrate 303 using CSD. Ti alkoxide was used as a raw material, 304 and the surfactant Tween 80 was included in the sol. The pore diameter measured using N₂ adsorption 305 306 was 4 nm, and the pore ratio derived from the 307 cumulative pore volume and the true density value 308 was 46% [24]. These data suggest that the pore 309 diameters and porosity of films formed on substrates 310 by CSD depend significantly on the raw materials 311 and the coating process.

Figure 6 plots the relationship between the thickness 313 of the Al₂O₃ film deposited on SUS304L or fused 314 silica and the measured zeta potential. The zeta 315 potentials were nearly the same for both substrate 316 materials and increased slightly from + 40 to 317 + 50 mV as the thickness was increased. This indi-318 cated that the zeta potential of the coating was the 319 same, regardless of the electrical conductivity of the 320 substrate. Furthermore, these values were in agree-321 ment with previously reported electrophoresis data 322 for Al_2O_3 particles [18, 19]. For comparison, the zeta 323 potentials of bare SUS304L and fused silica substrates 324 were plotted on the same graph as zero film thick-325 ness. These substrates were heat-treated at 773 K for 326 327 30 min, as in the case of the coated substrates. The zeta potentials of SUS304L and the fused silica sub-328 strates were approximately -13 and -46 mV, 329 respectively. Fused silica had a negative potential 330 with a larger absolute value. The zeta potential of the 331

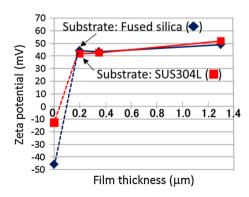


Figure 6 Relationship between film thickness and zeta potential for Al_2O_3 films coated on SUS304L and fused silica substrates (solution pH: 5.5).

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fused silica substrate agreed well with the results of
previously reported electrophoresis measurements
on SiO₂ particles [20, 21].

Figure 7 shows the relationship between the 335 336 number of measurements taken and the measured zeta potential for specimens with an Al₂O₃ film 337 thickness of about 1.3 µm. Results for uncoated 338 339 SUS304L and fused silica substrates are also plotted 340 on the same graph. The number of measurements did 341 not strongly affect the Al₂O₃-film-coated SUS304L 342 substrate, non-coated SUS304L substrate, and non-343 coated fused silica substrate. On the other hand, the 344 zeta potential clearly decreased for the Al₂O₃-coated 345 fused silica substrate; the total decrease was about 10 mV after six measurements. 346

347 Figure 8 shows the relationship between the 348 number of measurements taken and the measured 349 zeta potential for specimens with the Al₂O₃ films of 350 different thicknesses on a fused silica substrate. The 351 zeta potential decreased with increasing number of 352 measurements for all film thicknesses measured, 353 namely, 0.2 µm, 0.35 µm, and 1.3 µm, and the slope of 354 the decrease was roughly the same in each case. We proposed the following explanation for this phe-355 nomenon: The ceramic film formed by CSD typically 356 357 contains continuous pores. The electrolyte solution can penetrate these pores and reach the substrate 358 surface, producing the observed effect on the zeta 359 potential of the substrate. 360

361 Consideration for measured zeta potential

Figure 9 is a schematic depicting the aforementioned idea. When the zeta potential is measured using the streaming potential method, the electrolyte solution is pushed into the pores of the film because of the

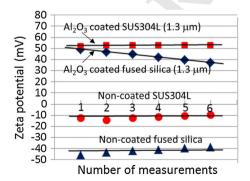


Figure 7 Relationship between number of measurements and zeta potential for Al_2O_3 -film-coated and non-coated substrates (solution pH: 5.5).

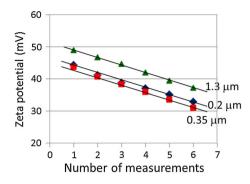
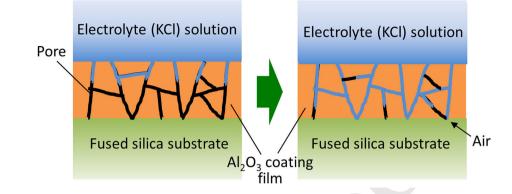


Figure 8 Relationship between number of measurements and zeta potential for Al_2O_3 films coated on fused silica substrates (solution pH: 5.5).

applied pressure. However, some of the air in the 366 pores of the film remains. This effect was more pro-367 nounced in the Al₂O₃ film on fused silica because the 368 zeta potential of the substrate (- 46 mV) was nega-369 tive and had a large absolute value. This effect was 370 also expected for the SUS304L substrate because in 371 this case, a film with similar continuous pores was 372 formed. However, the absolute value of the zeta 373 potential of the SUS304L substrate (- 13 mV) was 374 small, making the effect difficult to observe on this 375 substrate. 376

377 As shown in Fig. 5a, the pore diameter in the Al_2O_3 film obtained in this study was very small at 2 nm; 378 thus, its relationship with the hydration radius of the 379 ions in the electrolyte was considered. Figure 10 380 shows the relationship between the pore diameter in 381 the Al₂O₃ film and the hydration radius of the ions. 382 The hydration radius of both K⁺ and Cl⁻ is about 383 0.33 nm [25]. Therefore, a maximum of three ions can 384 be accommodated in the radial direction of the Al₂O₃ 385 film pores. As a result, it is necessary to confirm 386 whether the ions actually enter the pores. 387

Elemental analysis of K and Cl along the depth 388 direction of Al₂O₃ film was carried out for some 389 samples using dynamic secondary ion mass spec-390 trometry (D-SIMS; PH16600, Physical Electronics) 391 after zeta potential measurement. The samples were 392 based on specimens with an approximately 1.3-µm-393 thick Al₂O₃ film on a fused silica substrate. The zeta 394 potential was measured six times, after which the 395 sample was dried in air and then further dried at 396 180 °C for 1.5 h in air. For comparison, similar anal-397 yses were conducted for specimens that were coated 398 under the same conditions but were not subjected to 399 zeta potential measurement. The primary ions used 400 in the measurement were O_2^- for K analysis and Cs^+ 401 **Figure 9** Infiltration of the KCl electrolyte into the pores of the Al₂O₃ film.



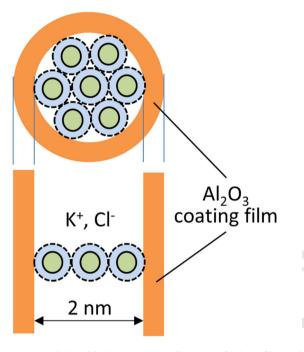


Figure 10 Relationship between pore diameter of Al_2O_3 film and hydration diameters of K^+ and Cl^- ions.

402 for Cl analysis. The analysis region was located at the 403 center of the specimen, with dimensions of approxi-404 mately 500 μ m × 500 μ m, and measurements were 405 conducted twice to confirm reproducibility. The 406 measurement results are given as the number of 407 atoms per number of Al₂O₃ atoms, based on the 408 predetermined standard curve.

409 Figure 11a, b shows the relationship between the 410 film depth and the K concentration of a specimen 411 before and after zeta potential measurement for 412 Al₂O₃ films with a thickness of approximately 1.3 μ m 413 on a fused silica substrate, respectively. In these fig-414 ures, the blue circles indicate K concentration in the 415 coating film. Analysis of these graphs must take into account the high surface roughness of the substrate 416

(Ra of 0.4 µm) and the bilayer structure of the sam-417 ples (substrate and film). The film depth was mea-418 sured using a step gauge, and the horizontal axis was 419 plotted assuming a constant sputtering rate. How-420 ever, the actual sputtering rate differs between the 421 Al₂O₃ film and fused silica substrate; thus, the hori-422 423 zontal axis is only for reference. Moreover, the amounts of Al and Si shown do not represent quan-424 titative data and are only provided for reference. 425 Figure 11 shows that the concentration of K in the 426 Al₂O₃ film was about 2×10^{-5} atom% prior to zeta 427 potential measurement but increased by approxi-428 mately two orders of magnitude to reach 2×10^{-3} -429 atom% after the measurement. This result indicated 430 that the K⁺ ions in the electrolyte solution penetrated 431 the pores in the Al₂O₃ film during the zeta potential 432 measurement. 433

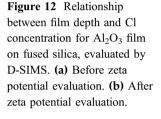
In this case, the coated specimen appeared to have 434 a higher K concentration as the depth increased. This 435 may have been caused by the presence of K in the 436 fused silica, which is partially sputtered. Different 437 matrices containing the same concentration of K do 438 not necessarily generate the same amount of sec-439 ondary ions in D-SIMS (matrix effect) [26]. Therefore, 440 we cannot be sure that the K concentration in Fig. 11a 441 actually increases with depth. On the other hand, 442 after zeta potential measurement, the K concentration 443 was constant up to a certain depth and then 444 decreased. Again, these values might include the 445 presence of K in the fused silica; hence, the change in 446 K concentration along the depth direction cannot be 447 discussed. 448

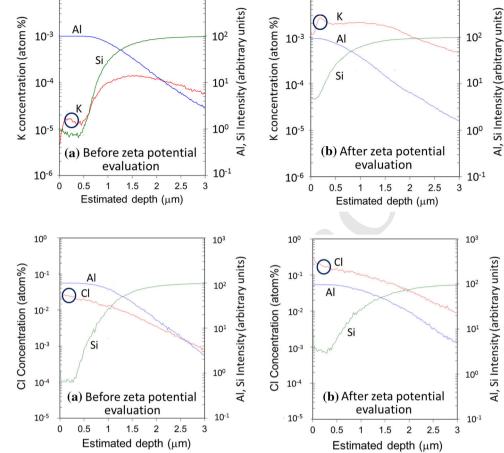
Figure 12a, b shows the relationship between the 449 film depth and the Cl concentration for an Al_2O_3 film 450 with a thickness of approximately 1.3 µm on a fused 451 silica substrate before and after zeta potential measurement, respectively. In these figures, the blue 453

10³

Figure 11 Relationship between film depth and K concentration for Al_2O_3 film on fused silica, evaluated by D-SIMS. **a** Before zeta potential evaluation. **b** After zeta potential evaluation.

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454 circles indicate Cl concentration in the coating film. 455 The concentration of Cl in the specimen was about 2×10^{-2} atom% prior to zeta potential measurement 456 but increased by approximately one order of magni-457 tude to 2×10^{-1} atom% after the measurement. This 458 459 result indicated that as with K⁺, the Cl⁻ ions in the electrolyte solution penetrated the pores in the Al₂O₃ 460 461 film during zeta potential measurement.

462 Comparing the specimens after zeta potential measurement (Figs. 11b, 12b), the concentrations of 463 K^+ and Cl^- ions were about 2×10^{-3} atom% and 464 2×10^{-1} atom%, respectively; that is, the concentra-465 tion of Cl⁻ was approximately 100 times that of K⁺. A 466 467 possible explanation for this difference is that the positive zeta potential of the surfaces of the pores in 468 469 the Al₂O₃ film at pH 5.5 [18, 19] facilitates the pene-470 tration of the oppositely charged Cl⁻ ions.

471 If the hypothesis in Fig. 9 is correct, a specimen
472 impregnated with the KCl electrolyte solution under
473 vacuum (to remove the remaining air in the pores)
474 should exhibit a constant zeta potential, even after

repeated measurements. Therefore, zeta potential 475 measurements were conducted after vacuum 476 impregnation of KCl electrolyte solution into the 477 coating specimen by the streaming potential method. 478

The vacuum impregnation method is shown in 479 Fig. 13. An Al_2O_3 film with a thickness of 1.3 μ m was 480 coated onto a fused silica substrate, which was held 481 in a PP container. The entire vacuum chamber 482 including PP container was evacuated for 30 min 483 using a rotary pump. Then, 1 mM KCl solution was 484 injected into the PP container. Evacuation was con-485 tinued for another 10 min; then, the vacuum was 486 released so that the chamber reached atmospheric 487 pressure. The PP container holding the specimen was 488 removed from the vacuum chamber, and a lid was 489 placed on the container. After the specimen was 490 allowed to rest for 120 h, the zeta potential was 491 measured. Figure 14 shows the relationship between 492 493 the number of measurements and the measured zeta potential. The zeta potential after vacuum impreg- AQ3-94 nation was constant at approximately 32 mV and did 495

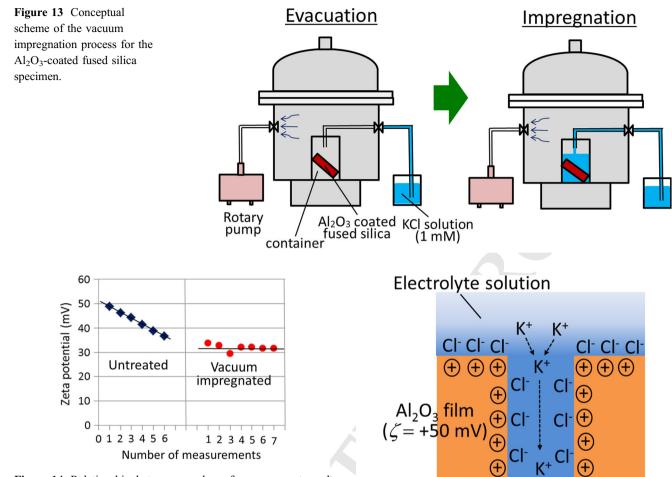


Figure 14 Relationship between number of measurements and zeta potential for untreated and vacuum-impregnated Al_2O_3 films coated on fused silica (film thickness: 1.3 µm).

496 not depend on the number of measurements per-497 formed. Therefore, the decrease in the zeta potential 498 with repeated measurements in Fig. 8 was due to the 499 fact that the KCl solution gradually penetrated the 500 Al_2O_3 film.

Figure 15 depicts the mechanism of the decrease in 501 502 the zeta potential that is implied from the experimental results above. The K⁺ and Cl⁻ ions in the 503 electrolyte penetrate the pores in Al₂O₃ due to the 504 505 pressurization during the zeta potential measure-506 ment. This penetration is gradual because some air remains in the Al₂O₃ pores. Cl⁻ ions are attracted to 507 the pores at the surface of the Al_2O_3 film, which has a 508 positive zeta potential, and form a fixed bed. In 509 contrast, K⁺ ions are attracted to the surface of the 510 511 fused silica substrate, which has a negative zeta potential, and form an electrical double layer. As a 512 513 result, a region in which K⁺ ions are depleted (de-514 pletion layer) is formed on the surface side of the

Figure 15 Mechanism of reduction in the zeta potential for Al_2O_3 film coated on fused silica substrate.

K⁺K⁺

(-)(-)(-)

Fused silica ($\zeta = -40 \text{ mV}$)

electrical double layer (upper side of Fig. 15). In 515 consequence, the K⁺ ions diffuse from the electrolyte 516 solution existing outside of the pores in the Al₂O₃ 517 film into this depletion layer, causing the region near 518 the Al₂O₃ film surface to become K⁺-rich, and the 519 anion concentration decreases. The zeta potential 520 measured using the streaming potential method 521 should correspond to the total charge of the ions near 522 the surface of the Al₂O₃ film, and thus, the zeta 523 potential decreases when the electrolyte solution 524 penetrates the pores of the film. 525

566

Conclusions 526

527 Al₂O₃ films were coated on SUS304L stainless steel 528 and fused silica substrates using CSD, and the con-529 tinuous pores with a diameter of approximately 2 nm 530 were observed in the films. The zeta potential of the 531 film was measured using the streaming potential 532 method. Initially, the measured zeta potential of the 533 Al_2O_3 films was + 40 to + 50 mV, which was the 534 same for both substrates. However, the zeta potential 535 of the Al₂O₃ film on the fused silica substrate 536 decreased significantly with repeated measurements. 537 It was considered that electrolyte solution penetrated 538 these pores and reached the fused silica substrate, 539 and thus, the zeta potential of the fused silica sub-540 strate gradually affected the measured zeta potential. 541 This is a characteristic phenomenon that occurs when 542 the zeta potential of a film containing continuous 543 pores is measured using the streaming potential 544 method. The streaming potential method is a supe-545 rior measurement method by which the zeta potential 546 of a film coated on a metal substrate can be mea-547 sured. However, when measuring a film with con-548 tinuous pores, it is necessary to pay attention to the 549 facts found in this study.

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Compliance with ethical standards 563

Conflict of interest There authors declare that they 564 have no conflict of interest. 565

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